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Bib Data Sheet

CONFIRMATION NO. 5893

SERIAL NUMBER 09/836,857	FILING DATE 04/17/2001 RULE	CLASS <del>427</del> 246	GROUP ART UNIT <del>1762</del> 1	ATTORNEY DOCKET NO. 12179-P098US	
<b>APPLICANTS</b> Seiichi Iwamatsu, Nagano, JAPAN;					
<b>** CONTINUING DATA **</b> <i>None</i>					
<b>** FOREIGN APPLICATIONS **</b> <i>None</i>					
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** SMALL ENTITY **</b> <b>** 06/14/2001</b>					
Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no 35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance		STATE OR COUNTRY JAPAN	SHEETS DRAWING 6	TOTAL CLAIMS 14	INDEPENDENT CLAIMS 2
Verified and Acknowledged Examiner's Signature <i>[Signature]</i> Initials <i>[Initials]</i>					
<b>ADDRESS</b> Winstead Sechrest & Minick P.C. 5400 Renaissance Tower 1201 Elm Street Dallas, TX 75270					
<b>TITLE</b> Electron beam duplication lithography method and apparatus					
<b>FILING FEE RECEIVED</b> 420	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:				
<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit					